

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No.10/671,922
Confirmation No.8459
Filing Date September 24, 2003
Inventor..... Garo J. Derderian et al.
Assignee.....Micron Technology, Inc.
Group Art Unit.....2812
ExaminerAhmadi, Mohsen
Attorney's Docket No.MI22-2296
Title: Atomic Layer Deposition Methods, and Methods of Forming Materials Over
Semiconductor Substrates

RESPONSE TO APRIL 25, 2007 OFFICE ACTION

To: Mail Stop Amendment
Commissioner for Patents
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AMENDMENTS

Introductory Comments

In reply to the Office Action of April 25, 2007, applicant amends and remarks as follows.